

Note Added in Proof

Contest

My apologies to you all; the note on page 38 is a spoof. My co-authors are a fictitious member of the electron microscopy group at Bristol University in the 1980s and a fictitious student we invented at my secondary school, half a century ago. In the case of the latter, we were able to persuade the teachers and administration that he was real for an entire term.

The whole point of the note was so that I can here claim that what we have done is to *re-invent the WHEEL*—Wavelength High-Energy Electron Localization. To make up for this fraud, *Microscopy Today* will be pleased to offer a prize for the best explanation, received prior to 1 May, 2010, of why WHEEL cannot work. The prize is a free registration to either M&M 2010 in Portland or M&M 2011 in Nashville.

WHEEL turns out to be very closely related to a method proposed many years earlier [1]. We are pleased that this allows us to add to the many tributes to the author of that earlier spoof [2].

Alwyn Eades

References

- [1] L Gandolfi and J Reiffel, "Enhancement of contrast in the CEM and STEM using bumpy specimens and employing the 'Dapled Field' mode of operation," *Proceedings of the Thirty-second Annual Meeting: Electron Microscopy Society of America* (1974) 552–553.
- [2] E Zeitler, "In memory of Judith Reiffel," *Ultramicroscopy* 100 (2004) vii–ix.

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The advertisement for ARC Nano includes the following elements:

- ARC Logo:** A stylized 'arc' logo in black with a blue swoosh underneath, and the website www.arcnano.com.
- SEM Image:** A scanning electron micrograph showing a single, dark, spherical particle on a textured surface. Metadata at the bottom reads: "S4700 7.0kV 16.0mm x3.50k SE(M) 12/3/08" and a scale bar for "10.0um".
- Technical Drawing:** A schematic of a circular disc with 15 holes arranged in a row. The holes are labeled "HOLE# 1" through "HOLE# 15". The drawing includes crosshair marks and is attributed to "Advanced Research Corporation 651 789 9000".
- Service List:** A list of services provided: SEM - FIB - IC Edit - AFM - Analytical Services - Failure Analysis - Testing Thin Films - Photolithography - Precision CNC Machining - Custom Tooling Custom Electronics - Flip Chip Services - Flip Chip Tooling - FC 150.

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